



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 09/421,625
Filing Date October 19, 1999
Inventor..... Eugene P. Marsh
Assignee..... Micron Technology, Inc.
Group Art Unit..... 2811
Examiner H. Vu
Attorney's Docket No. MI22-1284
Title: Circuitry and Capacitors Comprising Roughened Platinum Layers

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References - - See attached Form PTO-1449


In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the reference listed on the attached Form PTO-1449. No admission is made regarding whether the submitted reference is prior art.

This Supplemental Information Disclosure Statement is being filed after the filing of the Request for Continued Examination (RCE) Application and before receipt of the first Office Action. Therefore, no fee is believed to be required. However, in the event that a fee is required for filing this Supplemental Information Disclosure Statement, please charge the fee specified under 37 C.F.R. § 1.17(p) to Deposit Account No. 23-0925. Please credit Deposit Account No. 23-0925 with any overpayment of the above fee.

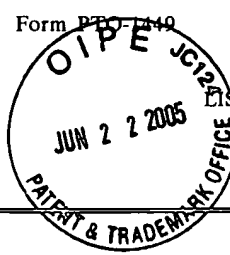
Citation of this reference is respectfully requested.

Respectfully submitted,

Date: 22 Jun 2005



James E. Lake
Reg. No. 44,854

Form PTO-140 		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-1284		SERIAL NO. 09/421,625	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Eugene P. Marsh			
FILING DATE October 19, 1999				GROUP 2811			

U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						

FOREIGN PATENT DOCUMENTS							
Document Number	Date	Country	Class	Subclass	Translation		
					Yes	No	
AM							
AN							
AO							
AP							
AQ							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)		
AR		Toru Nasu, et al, Study of Pt Bottom Electrodes Using High-Temperature Sputtering for Ferroelectric Memories with SrBi2Ta2O9 (SBTO) Film, Jpn. J. Appl. Phys. Vol. 37 (1998) pp. 4144-4148.
AS		

EXAMINER	DATE CONSIDERED
----------	-----------------

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.